

Growth of Eu-doped GaN using an oxygen-free liquid Eu source bis(*n*-propyltetramethylcyclopentadienyl)europium by organometallic vapor phase epitaxy and its luminescence properties

A. Koizumi¹, R. Wakamatsu¹, D. Lee¹, Y. Saitoh¹, Y. Kuboshima², Y. Mogi², S. Higashi², K. Kikukawa², H. Ofuchi³, T. Honma³, and Y. Fujiwara¹

¹ Graduate School of Engineering, Osaka University, 2-1 Yamadaoka, Suita, Osaka 565-0871, Japan
Email: koizumi@mat.eng.osaka-u.ac.jp

² Kojundo Chemical Laboratory Co., Ltd., 5-1-28, Chiyoda, Sakado, Saitama 350-0284, Japan

³ Japan Synchrotron Radiation Research Institute (JASRI/SPring-8), 1-1-1 Kouto, Sayo-cho, Hyogo 679-5198, Japan

1. Introduction

Red emission from GaN-based semiconductors is a key technology to realize a high-resolution monolithic full-color light-emitting display. The successful growth of Eu-doped GaN (GaN:Eu) by organometallic vapor phase epitaxy (OMVPE) and red light-emission from the GaN:Eu under the current injection has been reported [1]. For the Eu doping into GaN by OMVPE, an organometallic Eu source, tris(dipivaloylmetanato)europium [Eu(DPM)₃], has been extensively used due to its moderate vapor pressure. However, Eu(DPM)₃ has problems with instability of supply rate due to the solid source (melting point of 188°C) and including oxygen in the molecular structure, which is possible to degrade electrical characteristics of matrix materials. Recently, we have succeeded in the first synthesis of a new Eu organometallic source, bis(*n*-propyltetramethylcyclopentadienyl)europium [Eu(Cp^{pm})₂], which is an oxygen-free liquid Eu source at operating temperatures with moderate vapor pressure. In this contribution, we characterized luminescence properties of GaN:Eu grown using Eu(Cp^{pm})₂.

2. Experimental Approach and Results

The samples were grown on sapphire (0001) substrates by OMVPE. The Eu(Cp^{pm})₂ was used for the Eu source for Eu-doping on GaN. Eu(Cp^{pm})₂ was maintained at the temperatures in the range from 115 to 135°C. At the temperatures, the Eu source is liquid and can be supplied by bubbling method. A 300-nm thick GaN:Eu and 10-nm thick GaN capping layers were grown on undoped GaN buffer layer. The GaN:Eu grown using Eu(DPM)₃ with the same sample structure was used for comparison. The concentrations of both samples were determined $\sim 1 \times 10^{19} \text{ cm}^{-3}$ by fluorescent x-ray intensity compared with standard samples.

X-ray absorption near-edge structure (XANES) spectrum at Eu L_{III}-edge revealed that Eu ions incorporated into GaN using Eu(Cp^{pm})₂ were trivalent, while the Eu had a valence of two, *i.e.* divalent, in the Eu(Cp^{pm})₂. Therefore, divalent Eu in the Eu(Cp^{pm})₂ were oxidized during the growth and doped in GaN as trivalent Eu³⁺ ions.

Room-temperature photoluminescence (PL) spectra of GaN:Eu grown using Eu(Cp^{pm})₂ and Eu(DPM)₃ are shown in Fig. 1. The emission peaks associated with intra-4*f* shell transition from ⁵D₀ to ⁷F₂ in Eu³⁺ ions are observed in both samples. The GaN:Eu using Eu(Cp^{pm})₂ exhibits a

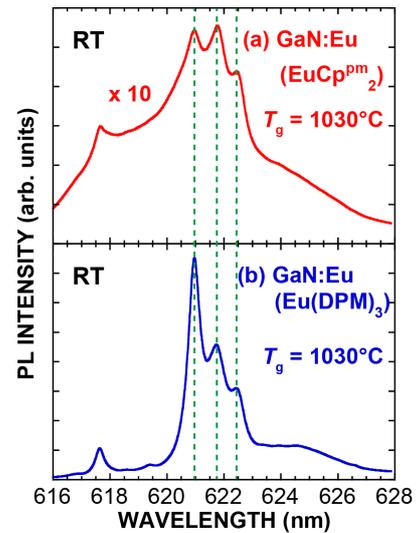


Fig. 1 Room-temperature PL spectra for the GaN:Eu grown using (a) Eu(Cp^{pm})₂ and (b) Eu(DPM)₃.

significantly broad emission spectrum, which is reflected in inhomogeneous emission lines due to fluctuation of the local structures of Eu³⁺ ions. Regardless of the broad emission spectrum, Eu(Cp^{pm})₂ has another advantage in obtaining abrupt doping profile, which improves the device performance electrically.

3. Conclusions

In summary, we have succeeded in growth of GaN:Eu using the oxygen-free liquid Eu source, Eu(Cp^{pm})₂, by OMVPE and observed red emission from the Eu³⁺ ions.

4. Open Questions

Open question to be discussed is as follows.

- What is the difference in the local structures between GaN:Eu using Eu(DPM)₃ and Eu(Cp^{pm})₂?

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References

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